

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
IMEC283.001AUSAPPLICATION NO.  
10/663,340SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT  
Rottenberg, et al.FILING DATE  
September 15, 2003GROUP  
~~2811~~

2818

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
dlu	1	4,211,488	07/08/80	Kleinknecht			
	2	6,323,951 B1	11/27/01	Borden, et al.			
	3	2002/0027660 A1	03/07/02	Borden, et al.			
	4	2002/0085211 A1	07/04/02	Borden, et al.			
dlu	5	2003/0043382 A1	03/06/03	Borden, et al.			

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	6	Sydor, et al., "Differential photoreflectance from modulation-doped heterojunctions", Applied Physics Letters, vol. 58, no. 9, pp. 948-950, (1991)
	7	International Search report dated March 24, 2004, for European Application No. 03 44 7186.

NO  
Copies  
Submitted.

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EXAMINER	<i>[Signature]</i>	DATE CONSIDERED	05/09/05
<p>*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 809; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.</p>			

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## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
dh	1.	WO 02/01584 A1	01/03/02	PCT			X	

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)							
dh	2.	Muldivin, et al., "High-isolation CPW MEMS shunt switches-Part 1: Modeling", IEEE Transactions on Microwave Theory and Techniques, vol. 48, no. 6, pp. 1045-1052, (June 2000).						
	3.	Nguyen, et al., "Micromachined devices for wireless communications", Proceedings of IEEE, vol. 86, no. 8, pp. 1756-1768, (August 1998)						
	4.	Rebeiz, et al., "RF MEMS switches and switch circuits", IEEE Microwave Magazine, pp. 59-71, (December 2001).						
	5.	Tilmans, et al., "Wafer-level packaged RF-MEMS switches fabricated in a CMOS fab", IEEE, pp. 921-924, (2001).						
	6.	Yao, et al., "Micromachined low-loss microwave switches", IEEE Journal of Microelectromechanical Systems, vol. 8, no. 2, (June 1999).						
dh	7.	Yao, J. Jason, "Topical Review: RF MEMS from a device perspective", J. Micromech. Microeng., vol. 10, pp. R9-R38, (2000).						

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EXAMINER	<i>Shaw</i>	DATE CONSIDERED	05/09/05
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.			